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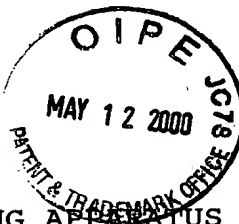
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): KATO, et al.

Serial No.: 09/552,572

Filed: April 19, 2000

For: VACUUM PROCESSING APPARATUS AND OPERATING
METHOD THEREFOR



SUPPLEMENTAL PRELIMINARY AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

May 12, 2000

Sir:

Supplementing the Preliminary Amendment filed April 19, 2000, please amend the above-identified application, prior to examination thereof, as follows:

IN THE CLAIMS

Please amend the claims presently in the application as follows:

a/ 2. (Amended) A method of transferring a substrate according to claim 1, wherein one of said two lock chambers [have] has a function of a load lock chamber, [or] and the other of said two lock chambers has a function of an unload lock chamber.

REMARKS

Applicants have amended their claims in order to further clarify claim 2, to specify that one of the two lock chambers has a function of a load lock chamber and the other of the two